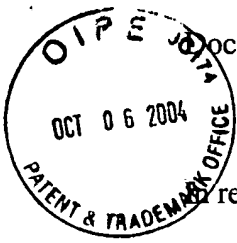


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Packet No.: 005917 USA/FET/FET

PATENT/OFFICIAL

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re Application of

Young Joseph PAIK

Serial No. 09/998,372

Filed: November 30, 2001

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: Group Art Unit: 3723
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: Examiner: Robert A. Rose

For: CONTROL OF CHEMICAL MECHANICAL POLISHING PAD CONDITIONER
DIRECTIONAL VELOCITY TO IMPROVE PAD LIFE

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This submission does not constitute a representation that a search has been made or that no better art exists and does not constitute an admission or representation that any of the listed documents is material or constitutes prior art. If it should be determined that any of the listed documents does not constitute prior art under the United States law, Applicants reserve the right

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Serial No. 09/998,372

to present to the Office the relevant facts and law regarding the appropriate status of such document.

Please charge the fee of \$180.00 to Deposit Account No. 08-0219. The Commissioner is hereby authorized to charge any additional fees that may be required for this submission, or credit any overpayment to deposit account no. 08-0219.

Respectfully submitted,

Wilmer Cutler Pickering Hale and Dorr LLP

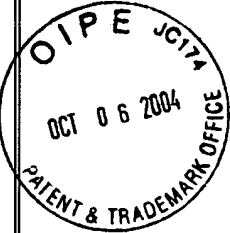


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<p style="text-align: center;">INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)</p> 	<p>ATTY. DOCKET NO. 005917 USA/FET/FET</p>	<p>SERIAL NO. 09/998,372</p>
	<p>APPLICANT Young Joseph PAIK</p>	
	<p>FILING DATE November 30, 2001</p>	<p>GROUP 3723</p>
<p style="text-align: center;">OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)</p>		
	<p>IslamRaja, M. M., C. Chang, J. P. McVittie, M. A. Cappelli, and K. C. Saraswat. May/June 1993. "Two Precursor Model for Low-Pressure Chemical Vapor Deposition of Silicon Dioxide from Tetraethylorthosilicate." <i>J. Vac. Sci. Technol. B</i>, Vol. 11, No. 3, pp. 720-726.</p>	
	<p>Kim, Eui Jung and William N. Gill. July 1994. "Analytical Model for Chemical Vapor Deposition of SiO₂ Films Using Tetraethoxysilane and Ozone" (Abstract). <i>Journal of Crystal Growth</i>, Vol. 140, Issues 3-4, pp. 315-326.</p>	
	<p>Guo, R.S, A. Chen, C.L. Tseng, I.K. Fong, A. Yang, C.L. Lee, C.H. Wu, S. Lin, S.J. Huang, Y.C. Lee, S.G. Chang, and M.Y. Lee. June 16-17, 1998. "A Real-Time Equipment Monitoring and Fault Detection System." <i>Semiconductor Manufacturing Technology Workshop</i>, pp. 111-121.</p>	
	<p>Lantz, Mikkel. 1999. "Equipment and APC Integration at AMD with Workstream." <i>IEEE</i>, pp. 325-327.</p>	
	<p>July 15, 2004. Office Action for U.S. Serial No. 10/172,977, filed June 18, 2002.</p>	
	<p>August 2, 2004. Office Action for U.S. Serial No. 10/174,377, filed June 18, 2002.</p>	
	<p>August 9, 2004. Written Opinion for PCT Serial No. PCT/US02/19063.</p>	
	<p>August 18, 2004. International Preliminary Examination Report for PCT Serial No. PCT/US02/19116.</p>	
	<p>August 24, 2004. Office Action for U.S. Serial No. 10/135,405, filed May 1, 2002.</p>	
	<p>August 25, 2004. Office Action for U.S. Serial No. 09/998,384, filed November 30, 2001.</p>	
	<p>September 9, 2004. Written Opinion for PCT Serial No. PCT/US02/21942.</p>	
	<p>September 16, 2004. International Preliminary Examination Report for PCT Serial No. PCT/US02/24859.</p>	
<p>EXAMINER</p>	<p>DATE CONSIDERED</p>	

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.